



(12) **United States Design Patent**  
**Krishnan et al.**

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(54) **CHEMICAL VAPOR DEPOSITION WAFER CARRIER WITH THERMAL COVER**

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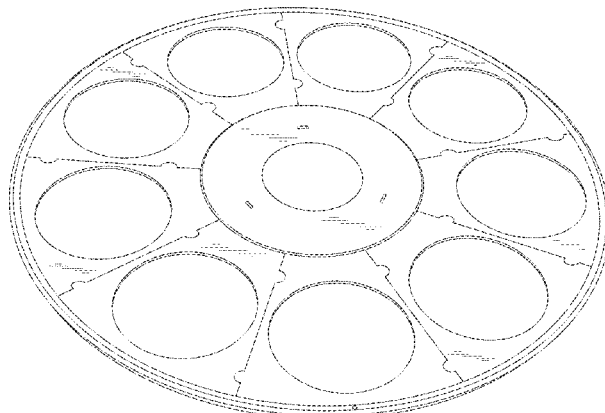
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See application file for complete search history.

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## (57) CLAIM

The ornamental design for a chemical vapor deposition wafer carrier with thermal cover, as shown and described.

## DESCRIPTION

FIG. 1 is a perspective view of a chemical vapor deposition wafer carrier with thermal cover, showing our new design.

FIG. 2 is a top plan view thereof.

FIG. 3 is a right side view thereof, with the left side view, front view, and rear view being identical.

FIG. 4 is a bottom plan view thereof; and,

FIG. 5 is a perspective view of the thermal cover of the chemical vapor deposition wafer carrier with thermal cover, shown separately for ease of illustration.

The broken lines in FIG. 4 form no part of the claimed design.

**1 Claim, 5 Drawing Sheets**

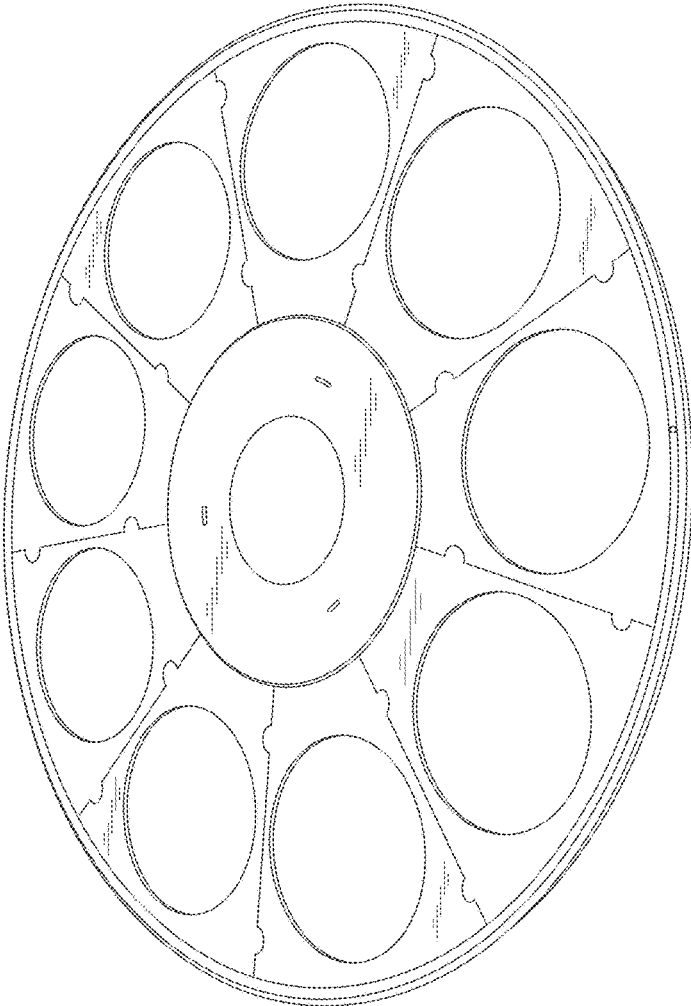


FIG. 1

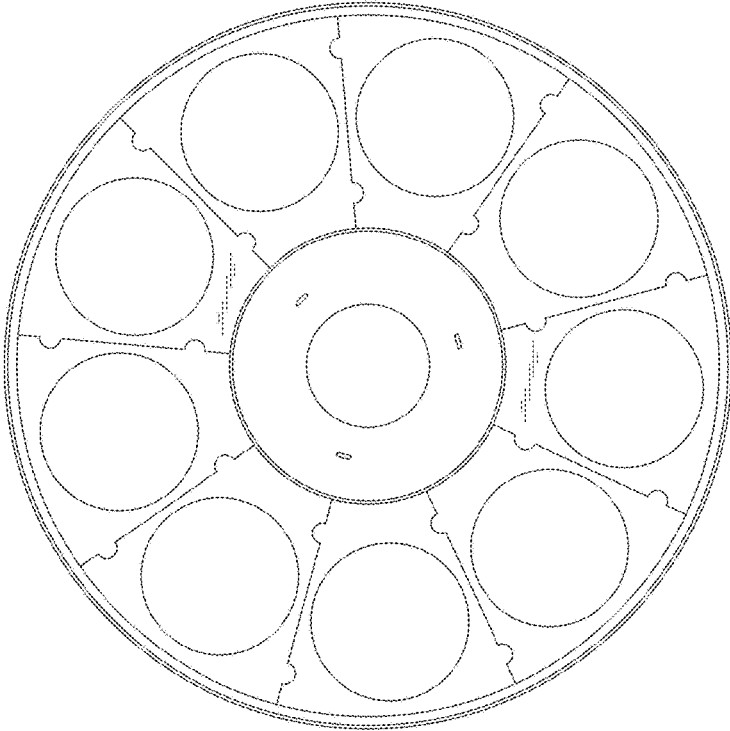


FIG. 2



FIG. 3

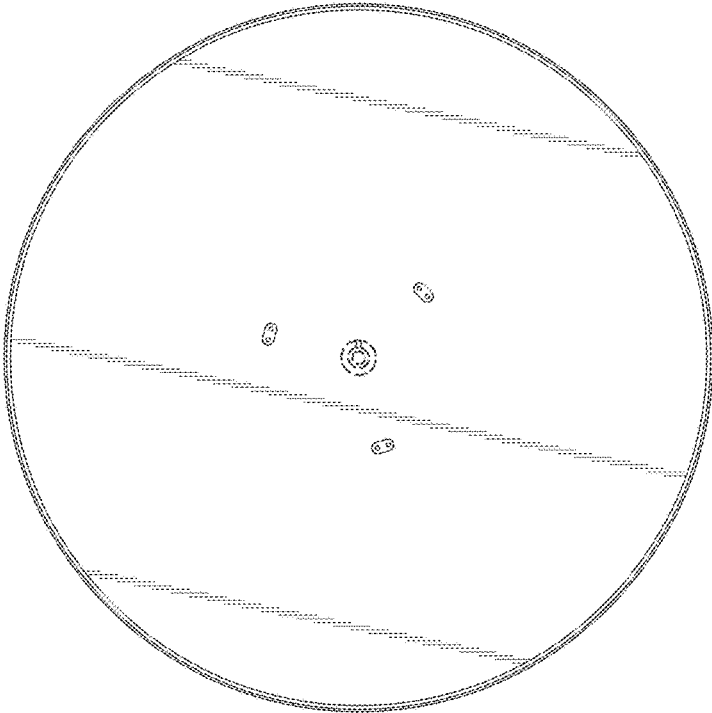


FIG. 4

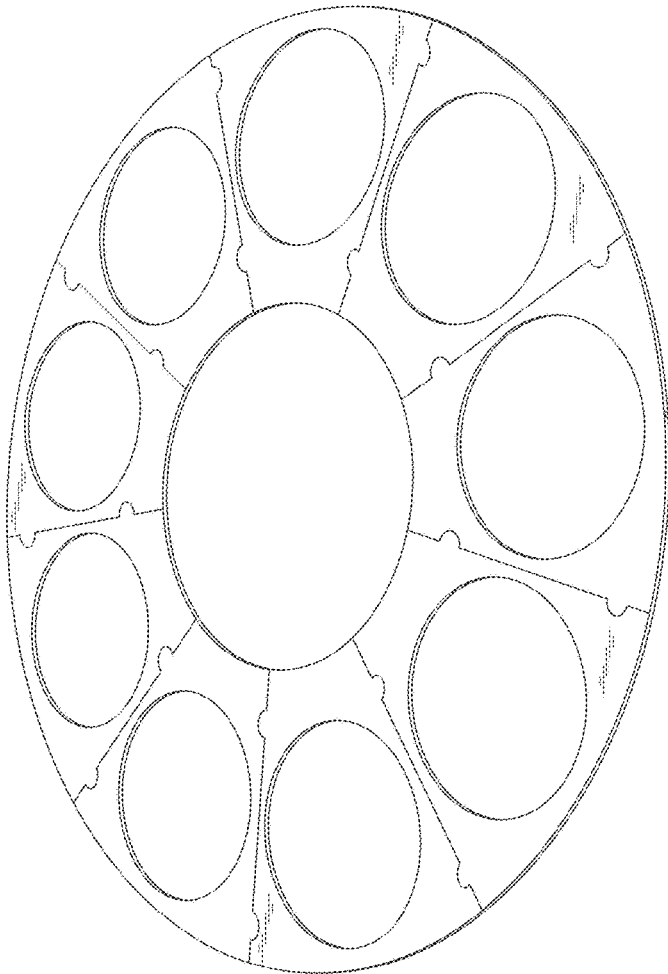


FIG. 5